

10/004714  
12/05/01

PATENT NUMBER and  
ISSUE DATE

U.S. UTILITY Patent Application

APPL NUM	FILING DATE	CLASS	SUBCLASS	GAU	EXAMINER
10004714	12/05/2001	257	306	2614	PERALTA

\*\*APPLICANTS: Meikle Scott; Dcan Trung;

708

\*\*CONTINUING DATA VERIFIED:

THIS APPLICATION IS A DIV OF 09/537,238 03/28/2000 WHICH IS A DIV OF 08/977,800 11/25/1997 WHICH IS A CON OF 08/667,907 06/12/1996 PAT 5,691,235 WHICH IS A CON OF 08/342,646 11/30/1994 ABN

\*\* FOREIGN APPLICATIONS VERIFIED:

PG-11B DO NOT PUBLISH <input type="checkbox"/>	RESCIND <input type="checkbox"/>
Request for priority claimed 35 USC 119 conditions met Verified and Acknowledged Examiner's initials	<input type="checkbox"/> yes <input type="checkbox"/> no <input type="checkbox"/> yes <input type="checkbox"/> no
ATTORNEY DOCKET NO 303.444USS	
TITLE : Method of depositing tungsten nitride using a source gas comprising silicon	
U.S. DEPT. OF COMM./PAT. & TM-PTO-435L (Rev. 12-91)	

NOTICE OF ALLOWANCE MAILED		CLAIMS ALLOWED	
		Assistant Examiner	
ISSUE FEE		Total Claims <input type="checkbox"/> Print Claim for O.G.	
Amount Due	Date Paid	DRAWING	
		Sheets Drwg.	Figs.Drwg.
		Print Fig.	
		Primary Examiner	
		PREPARED FOR ISSUE	
		Application Examiner	
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CD-ROM  
(Attached in pocket on right inside flap)

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